

THE INVENTION CLAIMED IS:

1. A standardized facilities box comprising:

a box;

a mechanism for mounting the box to a support

5 pedestal of a semiconductor fabrication facility; and

one or more mechanisms for selectively coupling any one of a set of add-on features within the box.

10 2. The standardized facilities box of claim 1

further comprising an add-on feature coupled to the one or more mechanisms for selectively coupling.

15 3. The standardized facilities box of claim 2

wherein the add-on feature comprises a partition.

20 4. The standardized facilities box of claim 2

wherein the add-on feature comprises a document storage compartment.

25 5. The standardized facilities box of claim 2

wherein the add-on feature comprises a sensor and a warning indicator.

30 6. The standardized facilities box of claim 2

wherein the add-on feature comprises an automatic lockout mechanism.

7. The standardized facilities box of claim 2

wherein the add-on feature comprises a tool storage

30 mechanism.

8. The standardized facilities box of claim 2

wherein the add-on feature comprises a support leg.

35 9. The standardized facilities box of claim 2

wherein the add-on feature comprises a bridge mechanism adapted to interface between the mechanism for mounting the box and a support pedestal.

10. The standardized facilities box of claim 2 wherein the add-on feature comprises a mechanical locating mechanism for a facilities connection.

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11. The standardized facilities box of claim 2 wherein the add-on feature comprises another standardized facilities box comprising:

a box;

10 a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and
one or more mechanisms for selectively coupling any one of a set of add-on features to the box.

12. The standardized facilities box of claim 2 wherein the add-on feature comprises an openable cover.

13. The standardized facilities box of claim 2 wherein the add-on feature comprises floor lighting.

14. The standardized facilities box of claim 2 wherein the add-on feature comprises a lifting mechanism adapted to lift and/or lower the box into or from a position for mounting the box to a support pedestal.

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15. The standardized facilities box of claim 2 wherein the add-on feature comprises a lifting mechanism adapted to lift and/or lower an item to or from the box.

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16. A facilities box comprising:

a box;

a mechanism for mounting the box to a raised floor tile of a semiconductor fabrication facility; and
a support leg coupled to the box for supporting the box.

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17. A facilities box comprising:

a box adapted to house facilities connections
therein;

a mechanism for mounting the box to a support
pedestal of a semiconductor fabrication facility; and

5 a lifting mechanism coupled to the box adapted to
lift and/or lower the box into or from a position for
mounting the box to a support pedestal.

18. A facilities box comprising:

10 a box adapted to house facilities connections
therein;

a mechanism for mounting the box to a support
pedestal of a semiconductor fabrication facility; and

15 a lifting mechanism adapted to lift and/or lower
an item to or from the box.

19. A facilities box comprising:

20 a box adapted to house facilities connections
therein;

a mechanism for mounting the box to a support
pedestal of a semiconductor fabrication facility; and
a sensor.

20. A facilities box comprising:

25 a box adapted to house facilities connections
therein;

a mechanism for mounting the box to a support
pedestal of a semiconductor fabrication facility; and
an exhaust mechanism.

30 21. A facilities box comprising:

a box adapted to house facilities connections
therein;

a mechanism for mounting the box to a support
35 pedestal of a semiconductor fabrication facility;

a cover coupled to the box; and

a lockout mechanism adapted to lock the cover of
the box.

22. The facilities box of claim 21 wherein the lockout mechanism is a lockout tag out mechanism.

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23. A method of standardizing a semiconductor fabrication facility, comprising:

indicating a location within a fabrication facility for installing a facilities box;

10 providing a standardized facilities box having a mechanism for selectively coupling any one of a set of add-on features to the standardized facilities box;

providing a plurality of add-on features; and

15 specifying which add-on feature should be selectively coupled to which selective coupling mechanism of the standardized facilities box.

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